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ATTORNEY DOCKET NO. CONFIRMATION NO. APPLICATION NO. FILING DATE FIRST NAMED INVENTOR 07/08/2003 AMAT/8241/CMP/ECP/RKK 1645 10/616,097 Zhi-Wen Sun EXAMINER 01/10/2006 44257 7590 PATTERSON & SHERIDAN, LLP WONG, EDNA 3040 POST OAK BOULEVARD, SUITE 1500 ART UNIT PAPER NUMBER HOUSTON, TX 77056 1753

DATE MAILED: 01/10/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

Advisory Action Before the Filing of an Appeal Brief

| Application No. | Applicant(s) | |
|-----------------|--------------|--|
| 10/616,097 | SUN ET AL. | |
| Examiner | Art Unit | |
| Edna Wong | 1753 | |

| | Edna Wong | 1753 | | |
|---|---|--|--|--|
| The MAILING DATE of this communication appe | ears on the cover sheet with the | correspondence add | ress | |
| THE REPLY FILED 30 December 2005 FAILS TO PLACE THIS APPLICATION IN CONDITION FOR ALLOWANCE. | | | | |
| 1. The reply was filed after a final rejection, but prior to or or this application, applicant must timely file one of the follow places the application in condition for allowance; (2) a Not a Request for Continued Examination (RCE) in compliant time periods: | wing replies: (1) an amendment, af otice of Appeal (with appeal fee) in one with 37 CFR 1.114. The reply m | fidavit, or other evider compliance with 37 C | nce, which FR 41.31; or (3) | |
| a) The period for reply expires <u>3</u> months from the mailing date | | | | |
| b) The period for reply expires on: (1) the mailing date of this A no event, however, will the statutory period for reply expire I Examiner Note: If box 1 is checked, check either box (a) or | ater than SIX MONTHS from the mailin (b). ONLY CHECK BOX (b) WHEN THI | g date of the final rejecti | ion. | |
| TWO MONTHS OF THE FINAL REJECTION. See MPEP 7 Extensions of time may be obtained under 37 CFR 1.136(a). The date | | 136(a) and the appropria | ite extension fee | |
| have been filed is the date for purposes of determining the period of ex under 37 CFR 1.17(a) is calculated from: (1) the expiration date of the set forth in (b) above, if checked. Any reply received by the Office late may reduce any earned patent term adjustment. See 37 CFR 1.704(b) NOTICE OF APPEAL | tension and the corresponding amount shortened statutory period for reply orig r than three months after the mailing da | of the fee. The approprince in the final Office of the final Offic | iate extension fee ice action; or (2) as | |
| The Notice of Appeal was filed on A brief in comp filing the Notice of Appeal (37 CFR 41.37(a)), or any external a Notice of Appeal has been filed, any reply must be filed. | nsion thereof (37 CFR 41.37(e)), to | o avoid dismissal of th | ns of the date of ie appeal. Since | |
| <u>AMENDMENTS</u> | | | | |
| 3. The proposed amendment(s) filed after a final rejection, | | | ecause | |
| (a) ☐ They raise new issues that would require further co (b) ☐ They raise the issue of new matter (see NOTE below) | | TE below); | | |
| (c) They are not deemed to place the application in be appeal; and/or | | ducing or simplifying | the issues for | |
| (d) They present additional claims without canceling a | corresponding number of finally rej | jected claims. | | |
| NOTE: (See 37 CFR 1.116 and 41.33(a)). | | | | |
| 4. The amendments are not in compliance with 37 CFR 1.1 | | mpliant Amendment | (PTOL-324). | |
| 5. Applicant's reply has overcome the following rejection(s) | | | | |
| 6. Newly proposed or amended claim(s) would be anon-allowable claim(s). | | | | |
| 7. For purposes of appeal, the proposed amendment(s): a) how the new or amended claims would be rejected is pro The status of the claim(s) is (or will be) as follows: Claim(s) allowed: Claim(s) objected to: | ☐ will not be entered, or b) ☒ wivided below or appended. | Il be entered and an e | explanation of | |
| Claim(s) objected to: Claim(s) rejected: 8-10,20-22 and 31-33. Claim(s) withdrawn from consideration: | | | | |
| AFFIDAVIT OR OTHER EVIDENCE | | | | |
| The affidavit or other evidence filed after a final action, but because applicant failed to provide a showing of good an was not earlier presented. See 37 CFR 1.116(e). | at before or on the date of filing a N d sufficient reasons why the affidate | otice of Appeal will <u>no</u> vit or other evidence is | ot be entered s necessary and | |
| 9. The affidavit or other evidence filed after the date of filing entered because the affidavit or other evidence failed to showing a good and sufficient reasons why it is necessar | overcome <u>all</u> rejections under appe | al and/or appellant fai | ils to provide a | |
| 10. ☐ The affidavit or other evidence is entered. An explanation REQUEST FOR RECONSIDERATION/OTHER | | • | | |
| 11. ☑ The request for reconsideration has been considered bu See pages 2-10. | t does NOT place the application in | n condition for allowar | nce because: | |
| 12. Note the attached Information Disclosure Statement(s). (PTO/SB/08 or PTO-1449) Paper No(s). | | | | |
| 13. Other: | C_{α} | im 11/2 | | |
| | | mo Wara | | |
| • | | COURT VVINOR | | |

Edna Wong
Primary Examiner
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ADVISORY ACTION

This is in response to the Amendment dated December 30, 2005. The text of those sections of Title 35, U.S. Code not included in this action can be found in a prior Office action.

Response to Arguments

Claim Rejections - 35 USC § 103

I. Claims 1-7 and 34 have been rejected under 35 U.S.C. 103(a) as being unpatentable over Miura et al. (US Patent Application Publication No. 2003/0155247 A1) in combination with Baskaran et al. (US Patent Application Publication No. 2004/0072419 A1).

The rejection of claims 1-7 and 34 under 35 U.S.C. 103(a) as being unpatentable over Miura et al. in combination with Baskaran et al. has been withdrawn in view of Applicants' amendment. Claims 1-7 and 34 have been cancelled.

II. Claims 8 and 9 have been rejected under 35 U.S.C. 103(a) as being unpatentable over Miura et al. (US Patent Application Publication No. 2003/0155247 A1) in combination with Baskaran et al. (US Patent Application Publication No. 2004/0072419 A1) as applied to claims 1-7 and 34 above, and further in view of Dubin et al. (US Patent No. 6,432,821 B1).

The rejection of claims 8 and 9 under 35 U.S.C. 103(a) as being unpatentable

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over Miura et al. in combination with Baskaran et al. as applied to claims 1-7 and 34 above, and further in view of Dubin is as applied in the Office Action dated October 4, 2005 and incorporated herein. The rejection has been maintained for the following reasons.

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III. Claim 10 has been rejected under 35 U.S.C. 103(a) as being unpatentable over Miura et al. (US Patent Application Publication No. 2003/0155247 A1) in combination with Baskaran et al. (US Patent Application Publication No. 2004/0072419 A1) as applied to claims 1-7 and 34 above, and further in view of Dubin et al. (US Patent No. 6,432,821 B1) as applied to claims 8 and 9 above, and further in view of Nagai et al. (US Patent No. 6,709,563 B2).

The rejection of claim 10 under 35 U.S.C. 103(a) as being unpatentable over Miura et al. in combination with Baskaran et al. as applied to claims 1-7 and 34 above, and further in view of Dubin et al. is as applied to claims 8 and 9 above, and further in view of Nagai et al. is as applied in the Office Action dated October 4, 2005 and incorporated herein. The rejection has been maintained for the following reasons.

IV. Claims 11, 13-15, 17-19 and 35 have been rejected under 35 U.S.C. 103(a) as being unpatentable over Miura et al. (US Patent Application Publication No. 2003/0155247 A1) in combination with Baskaran et al. (US Patent Application Publication No. 2004/0072419 A1).

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The rejection of claims 11, 13-15, 17-19 and 35 under 35 U.S.C. 103(a) as being unpatentable over Miura et al. in combination with Baskaran et al. has been withdrawn in view of Applicants' amendment. Claims 11, 13-15, 17-19 and 35 have been cancelled.

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V. Claims 20 and 21 have been rejected under 35 U.S.C. 103(a) as being unpatentable over Miura et al. (US Patent Application Publication No. 2003/0155247 A1) in combination with Baskaran et al. (US Patent Application Publication No. 2004/0072419 A1) as applied to claims 11, 13-15, 17-19 and 35 above, and further in view of Dubin et al. (US Patent No. 6,432,821 B1).

The rejection of claims 20 and 21 under 35 U.S.C. 103(a) as being unpatentable over Miura et al. in combination with Baskaran et al. as applied to claims 11, 13-15, 17-19 and 35 above, and further in view of Dubin et al. is as applied in the Office Action dated October 4, 2005 and incorporated herein. The rejection has been maintained for the following reasons.

VI. Claim 22 has been rejected under 35 U.S.C. 103(a) as being unpatentable over Miura et al. (US Patent Application Publication No. 2003/0155247 A1) in combination with Baskaran et al. (US Patent Application Publication No. 2004/0072419 A1) as applied to claims 11, 13-15, 17-19 and 35 above, and further in view of Dubin et al. (US Patent No. 6,432,821 B1) as applied to claims 20 and 21 above, and further in view of

Nagai et al. (US Patent No. 6,709,563 B2).

The rejection of claim 22 under 35 U.S.C. 103(a) as being unpatentable over Miura et al. in combination with Baskaran et al. as applied to claims 11, 13-15, 17-19 and 35 above, and further in view of Dubin et al. is as applied to claims 20 and 21 above, and further in view of Nagai et al. is as applied in the Office Action dated October 4, 2005 and incorporated herein. The rejection has been maintained for the following reasons.

VII. Claims 23-28, 30 and 36 have been rejected under 35 U.S.C. 103(a) as being unpatentable over Miura et al. (US Patent Application Publication No. 2003/0155247 A1) in combination with Baskaran et al. (US Patent Application Publication No. 2004/0072419 A1).

The rejection of claims 23-28, 30 and 36 under 35 U.S.C. 103(a) as being unpatentable over Miura et al. in combination with Baskaran et al. has been withdrawn in view of Applicants' amendment. Claims 23-28, 30 and 36 have been cancelled.

VIII. Claims 31 and 32 have been rejected under 35 U.S.C. 103(a) as being unpatentable over Miura et al. (US Patent Application Publication No. 2003/0155247 A1) in combination with Baskaran et al. (US Patent Application Publication No. 2004/0072419 A1) as applied to claims 23-28, 30 and 36 above, and further in view of Dubin et al. (US Patent No. 6,432,821 B1).

The rejection of claims 31 and 32 under 35 U.S.C. 103(a) as being unpatentable over Miura et al. in combination with Baskaran et al. as applied to claims 23-28, 30 and 36 above, and further in view of Dubin et al. is as applied in the Office Action dated October 4, 2005 and incorporated herein. The rejection has been maintained for the following reasons.

IX. Claim 33 has been rejected under 35 U.S.C. 103(a) as being unpatentable over Miura et al. (US Patent Application Publication No. 2003/0155247 A1) in combination with Baskaran et al. (US Patent Application Publication No. 2004/0072419 A1) as applied to claims 23-28, 30 and 36 above, and further in view of Dubin et al. (US Patent No. 6,432,821 B1) as applied to claims 31 and 32 above, and further in view of Nagai et al. (US Patent No. 6,709,563 B2).

The rejection of claim 33 under 35 U.S.C. 103(a) as being unpatentable over Miura et al. in combination with Baskaran et al. as applied to claims 23-28, 30 and 36 above, and further in view of Dubin et al. as applied to claims 31 and 32 above, and further in view of Nagai et al. is as applied in the Office Action dated October 4, 2005 and incorporated herein. The rejection has been maintained for the following reasons.

Applicants state that the Examiner has not supplied the requisite motivation to combine Miura, which discloses depositing a copper seed layer by a sputtering technique and electrolytic copper plating to fill or half fill trenches or via holes, with

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Baskaran, which discloses maintaining the alkaline electrolytic bath solution at a pH of at least about 9.0 and a citric acid bath solution has a suitable pH at about 9.5.

The Examiner has failed to show a clear and particular motivation by the skilled artisan to select from the entire disclosure of Baskaran, a reference to copper citrate for combination with Miura, while ignoring the remainder of Baskaran. On this point, the Federal Circuit has ruled that "[o]ne cannot use hindsight reconstruction to pick and choose among isolated disclosures in the prior art to deprecate the claimed invention." (*In re Fritch* at 1784).

The Examiner must show that the skilled artisan would be motivated to specifically select copper citrate from the eight potential copper sources listed in Baskaran for combining with Miura, despite Baskaran's failure to teach any particular advantages offered by copper citrate.

In response, Miura teaches that the copper ions may be added to the electrolytic copper plating solution in the form of <u>salts</u> (page 2, [0019], lines 3-4). <u>Salts of copper with the later-described complexing agent</u> are particularly preferred (page 2, [0020], lines 4-7). The later-described complexing agent includes <u>oxycarboxylic acid</u> (page 2, [0023]). The oxycarboxylic acid includes <u>citric acid</u> (page 2, [0027], line 2).

The salt of copper with citric acid is copper citrate. Thus, Miura teaches a copper solution containing complexed copper ions derived from a copper source of copper citrate.

Miura, alone, teaches copper citrate.

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Applicants state that the same chemical components are maintained throughout the various steps disclosed by Dubin.

In response, Miura teaches that current-reverse electrolysis is effective (page 4, [0054]). Dubin teaches current-reverse electrolysis (col. 5, lines 4-11; and Fig. 7).

As to the chemical components, the rejection is not overcome by pointing out that one reference does not contain a particular limitation when reliance for that teaching is on another reference. *In re Lyons* 150 USPQ 741 (CCPA 1966). Moreover, it is well settled that one cannot show nonobviousness by attacking the references individually where, as here, the rejection is based on a combination of references. *In re Keller* 208 USPQ 871 (CCPA 1981); *In re Young* 159 USPQ 725 (CCPA 1968).

Furthermore, claims 8, 20 and 31 recite that the complexed copper solution contains complexed copper ions derived from copper citrate, copper borate, copper tartrate, copper oxalate, derivatives thereof and combinations thereof; and the second copper solution contains free-copper ions. The complexed copper solution is opened to contain free copper ions and the second copper solution is opened to contain complexed copper ions. Thus, the solutions are not so different as presently claimed.

The Examiner maintains that Miura teaches depositing a seed layer. The PVD or CVD deposited seed layer (page 4, [0050]) incompletely fills the trenches and via holes with copper (page 1, [005]). Miura teaches that his electrolytic copper plating solution reinforces the seed layer and adds thickness to the seed layer within the trenches or via

holes (page 4, [0051]). These teachings would have suggested to one having ordinary skill in the art that (at least a part of) the seed layer is electrodeposited.

Miura teaches that when the electrolytic copper plating solution is applied tin the trenches or via holes of a silicon wafer, the trenches or via holes may be filled completely with copper using the electrolytic copper plating solution, or they may be filled halfway (= gap-fill) and then applied with a highly acidic or highly basic copper plating solution to be filled completely (= bulk-fill) [page 4, [0051]]. These teachings would have suggested to one having ordinary skill in the art that Miura discloses a gap-fill layer (= filled halfway) and a bulk-fill layer (= filled completely).

Applicants state that Nagai discloses these two plating liquids and remains completely silent to adding a leveling additive into the first plating liquid to form the second plating liquid. The Applicant does not find disclosure within Nagai of a third plating liquid or a third copper solution, as asserted by the Examiner.

In response, the test for obviousness is not whether the features of a secondary reference may be bodily incorporated into the structure of the primary reference; nor is it that the claimed invention must be expressly suggested in any one or all of the references. Rather, the test is what the combined teachings of the references would have suggested to those of ordinary skill in the art. See *In re Keller*, 642 F.2d 413, 208 USPQ 871 (CCPA 1981). Nagai teaches that using an additive for enhancing the leveling property would have given a flat plating surface. The use of the plating liquid

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having excellent leveling property can retard the growth of plating at the inlet of a fine recess. This makes it possible to fully fill the fine recesses with copper uniformly without formation of any voids, and further flatten the plating surface (col. 17, line 37 to col. 18, line 2). These teachings would have suggested to those of ordinary skill in the art that adding a leveler to the copper solution would have given a flat plating surface without the formation of any voids.

As to a third plating liquid or a third copper solution, the repetition of steps to provide the same results is within the skill of one having ordinary skill in the art. The concept of duplication is not patentable.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Edna Wong whose telephone number is (571) 272-1349. The examiner can normally be reached on Mon-Fri 7:30 am to 4:00 pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nam Nguyen can be reached on (571) 272-1342. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should

you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Edna Wong
Primary Examiner
Art Unit 1753

EW January 5, 2006